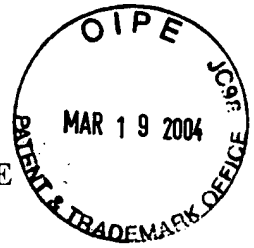


**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**



In re the Application of: **Shinichiroh IKEMASU, et al.**

Group Art Unit: **2814**

Serial No.: **10/050,169**

Examiner: **WEISS, Howard**

Filed: **January 18, 2002**

Confirmation No.: **9818**

For: **HIGHLY INTEGRATED AND RELIABLE DRAM AND ITS MANUFACTURE**

**INFORMATION DISCLOSURE STATEMENT**  
**PURSUANT TO 37 CFR 1.97(b)(4)**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

March 19, 2004

Sir:

The attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached Form PTO-1449. The documents were made of record in related application Serial No. 10/166,620, filed June 12, 2002.

The above information is presented so that the Patent and Trademark Office can, in the first instance, determine any materiality thereof to the claimed invention. See 37 CFR 1.104(a) concerning the PTO duty to consider and use any such information. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the documents cited in the attached Form PTO-1449 be made of record therein and appear on the first page of any patent to issue therefrom.



The Commissioner is authorized to charge our Deposit Account No. 50-2866 for any fee which is deemed by the Patent and Trademark Office to be required to effect consideration of this statement.

Respectfully submitted,

WESTERMAN, HATTORI, DANIELS & ADRIAN, LLP

A handwritten signature in black ink, appearing to read "Stephen G. Adrian".

Stephen G. Adrian  
Attorney for Applicant(s)  
Reg. No. 32,878

SGA/arf  
Enclosures: PTO-1449 and 18 References

Attorney Docket No. **970607B**

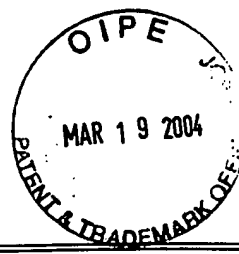
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<b>INFORMATION DISCLOSURE CITATION PTO-1449</b>	Atty. Docket No. 970607B	Serial No. 10/050,169
	Applicant(s): Shinichiroh IKEMASU et al.	
	Filing Date: January 18, 2002	Group Art Unit: 2814



### U.S. PATENT DOCUMENTS

Examiner Initial		Document No.	Name	Date	Class	Subclass	Filing Date (If appropriate)
_____	AA	5,605,857	Jost et al.	02/97			
_____	AB	5,324,681	Lowrey et al.	06/94			
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_____	AH						
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_____	AQ	B.M. SOMERO et al.; "A Modular in-situ Integration Scheme for Deep Submicron", Proceedings of 10 <sup>th</sup> International VMIC; pages 28-34; June 1993.
_____	AR	M.F. CHISHOLM et al.; "A High Performance 0.5 um Five-Level Metal Process with Extendibility of Sub-Half Micron"; pages 22-28; June 1994.
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_____	B A	
_____	BB	
<div>Examiner</div> <div>Date Considered</div>		